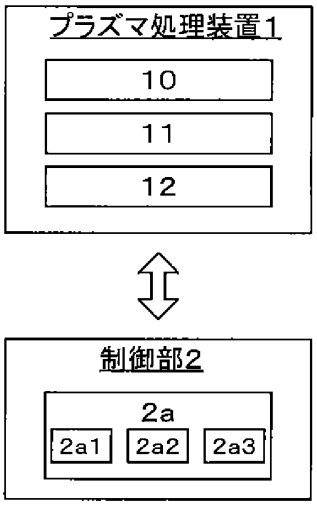
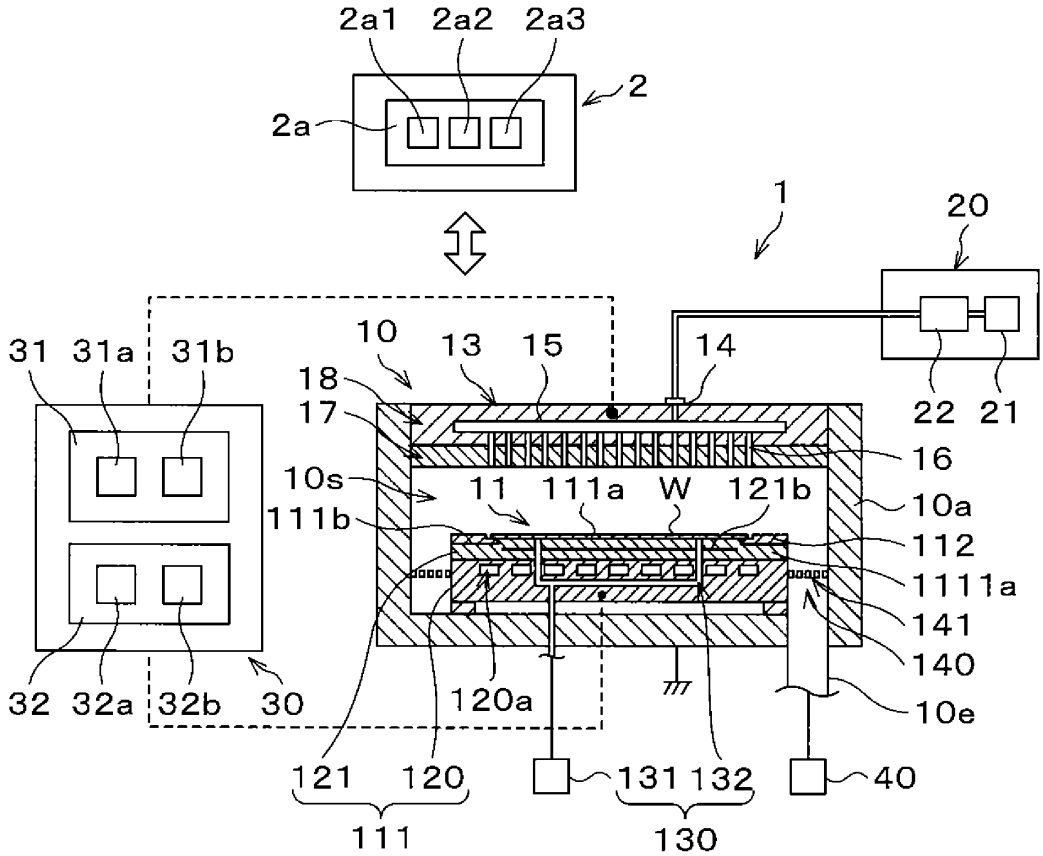
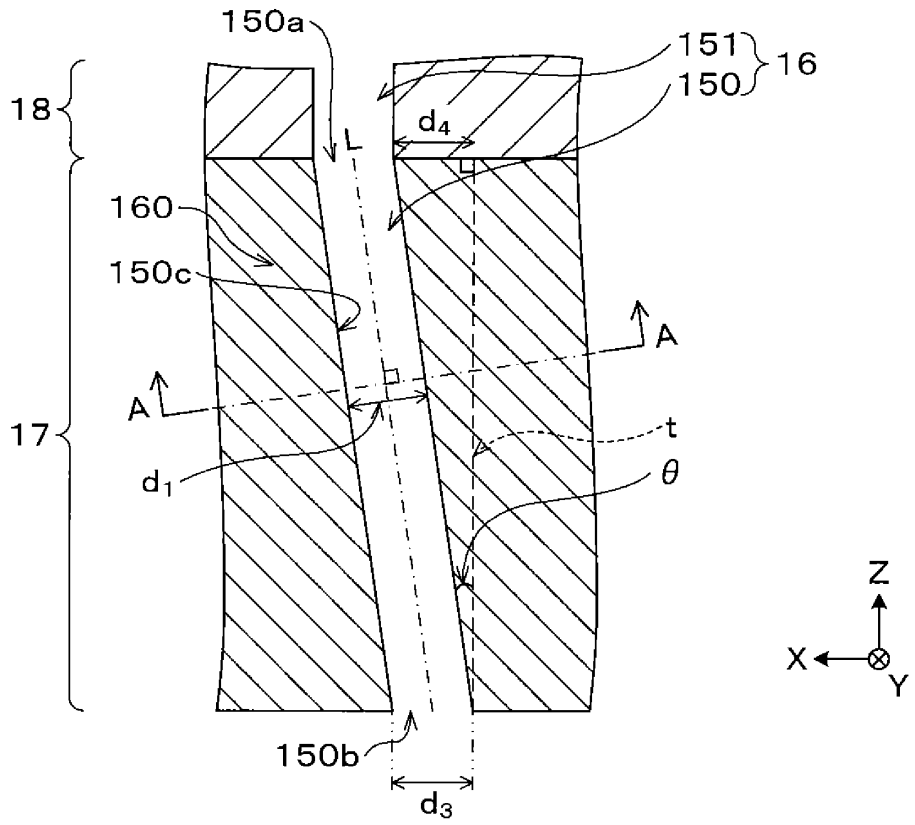
[図1]


プラズマ処理装置1
10
11
12
制御部2
2a
2a1
2a2
2a3

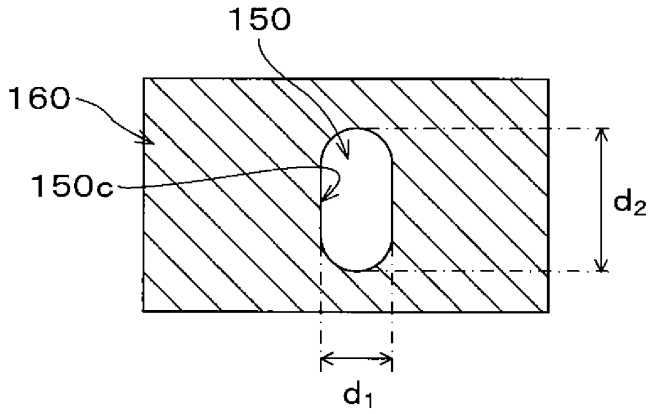
[図2]


2a1
2a2
2a3
2
2a
1
20
31
31a
31b
10
13
15
14
18
17
16
10s
11
111a
W
121b
10a
111b
112
1111a
141
140
10e
32
32a
32b
30
120a
121
120
131
132
40
111
130
22
21

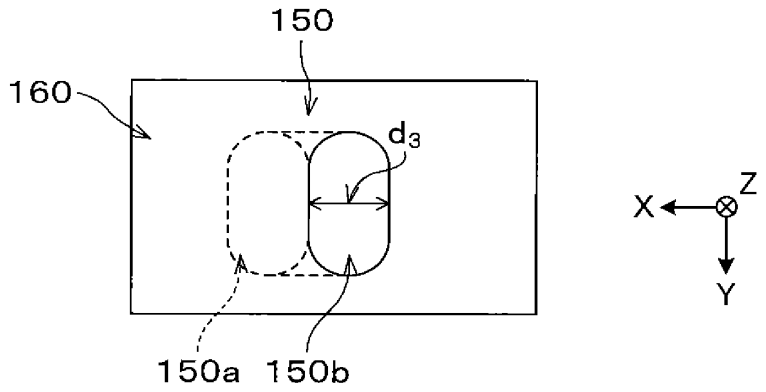
[図3]


150a
151
150
16
18
L
d4
160
150c
A
A
17
t
d1
θ
Z
X
Y
150b
d3

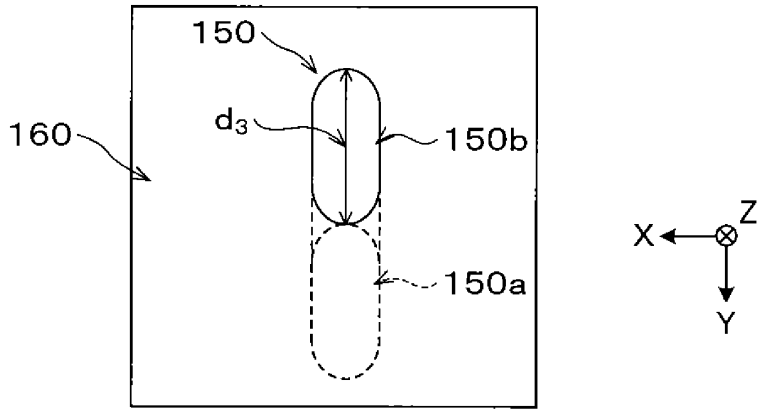
[図4]


150
160
150c
d2
d1

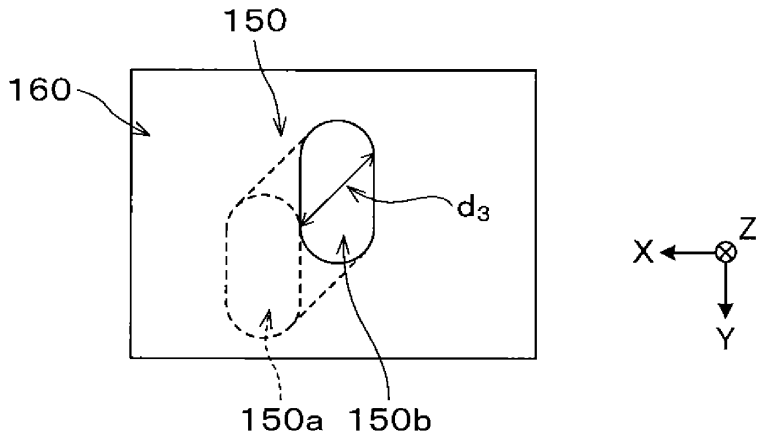
[図5]


150
160
d_3
150a
150b
X
Z
Y

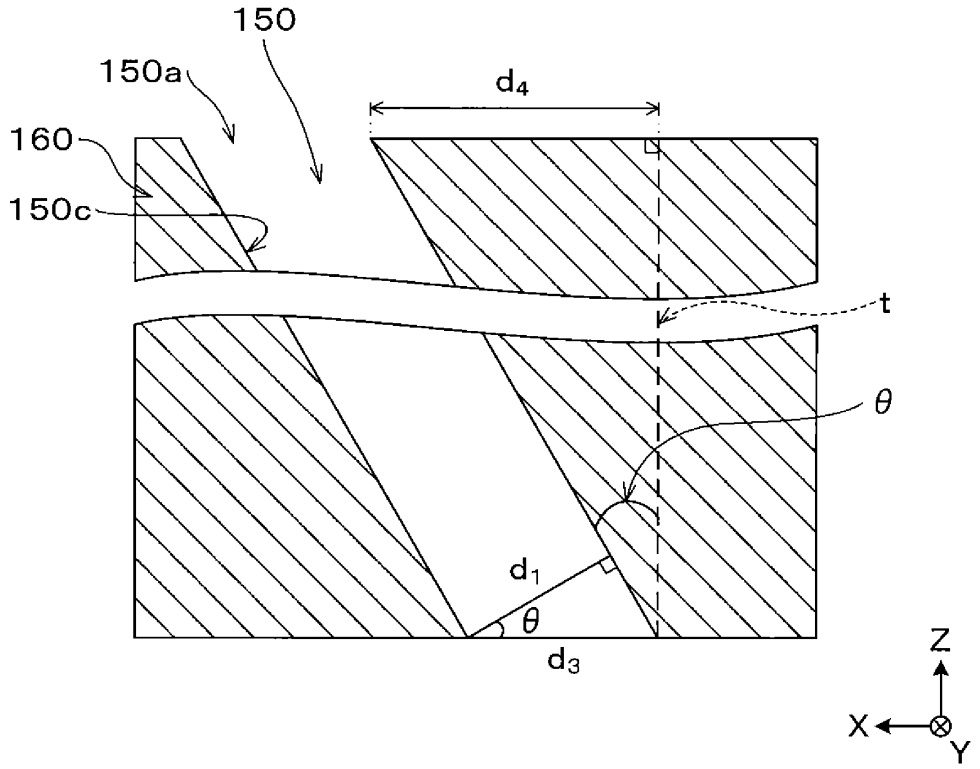
[図6]


150
160
d_3
150b
150a
X
Z
Y

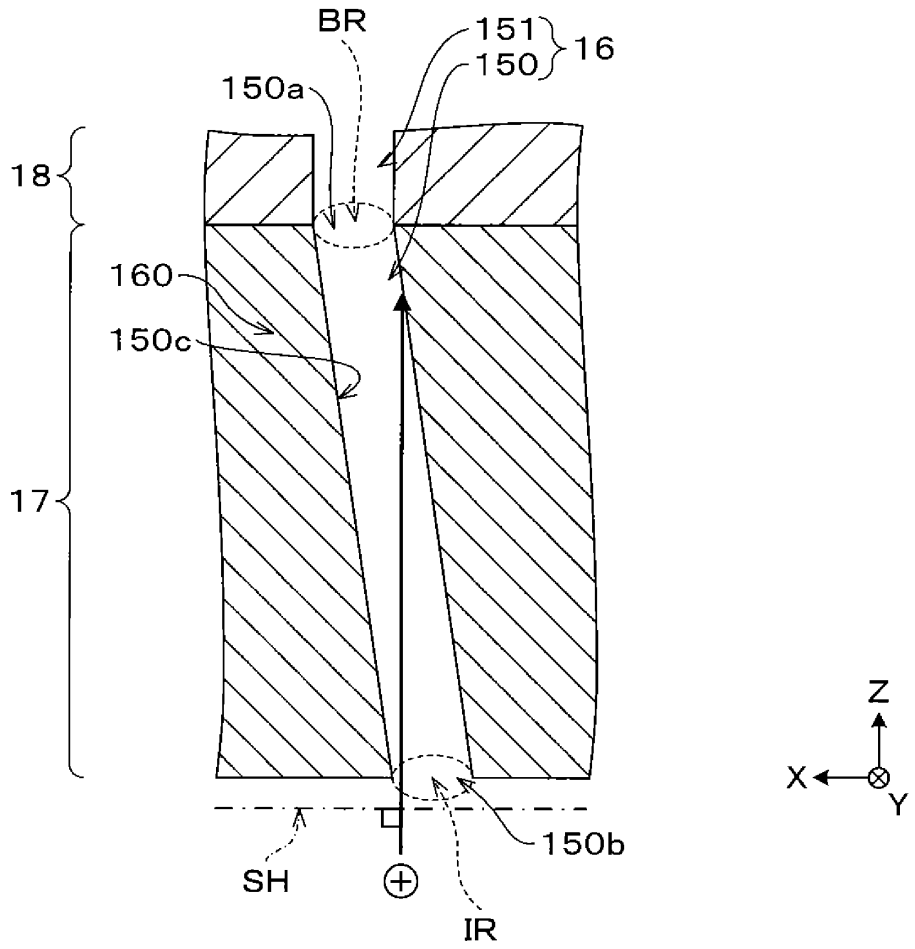
[図7]


150
160
d_3
150a
150b
X
Z
Y

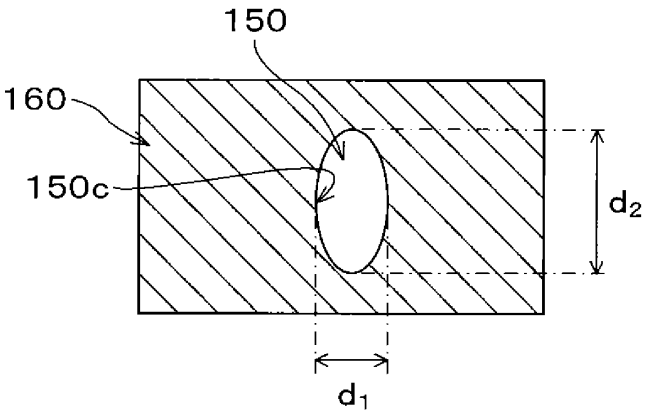
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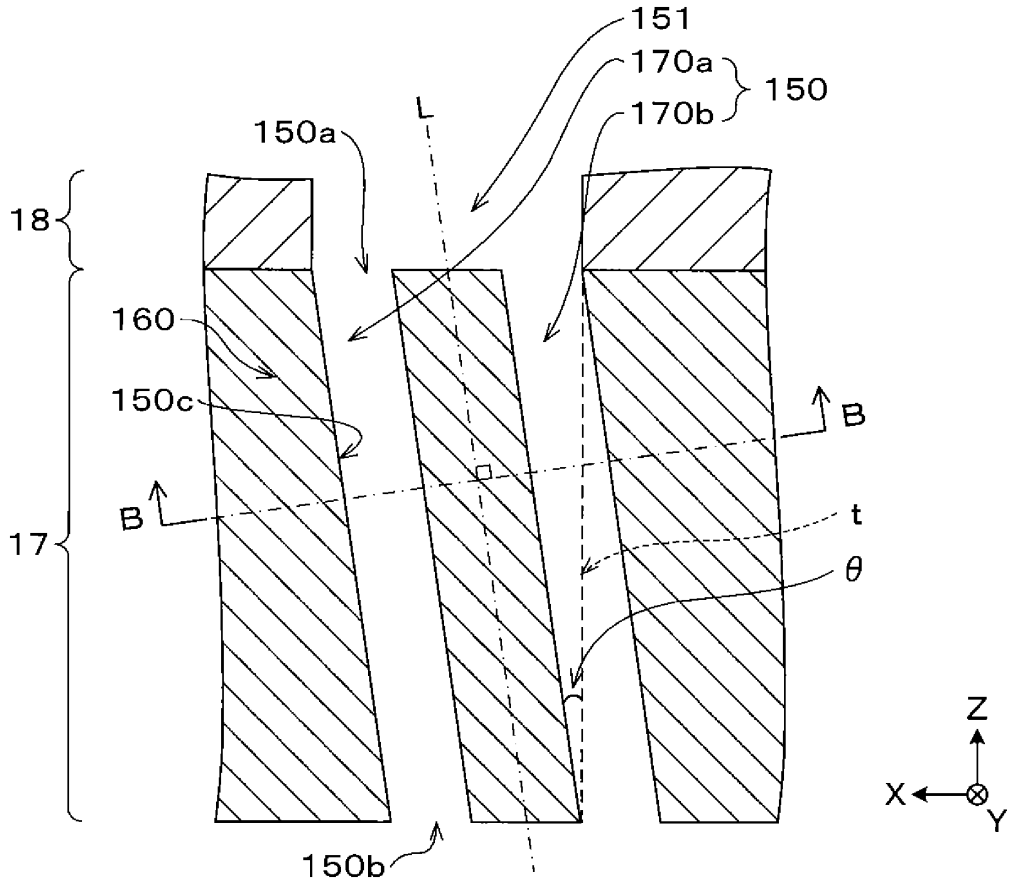
[図9]


BR
151
150
16
150a
18
160
150c
17
Z
X
Y
150b
SH
IR

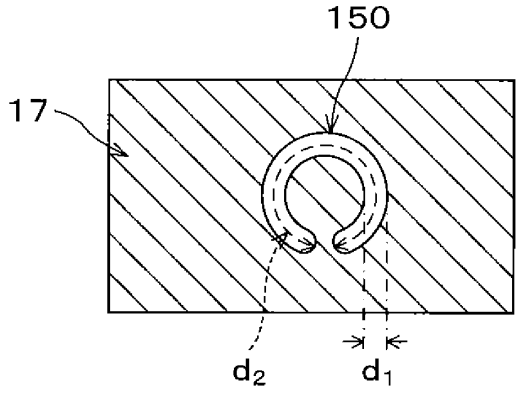
[図10]


150
160
150c
d_2
d_1

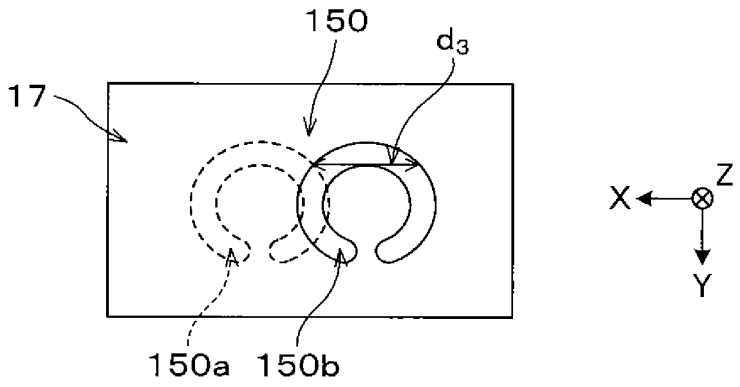
[図11]


151
170a
170b
150
150a
L
18
160
150c
B
B
17
t
θ
Z
X
Y
150b

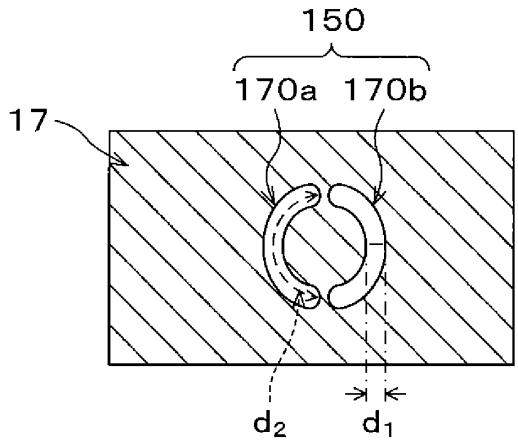
[図12]


150
17
d2
d1

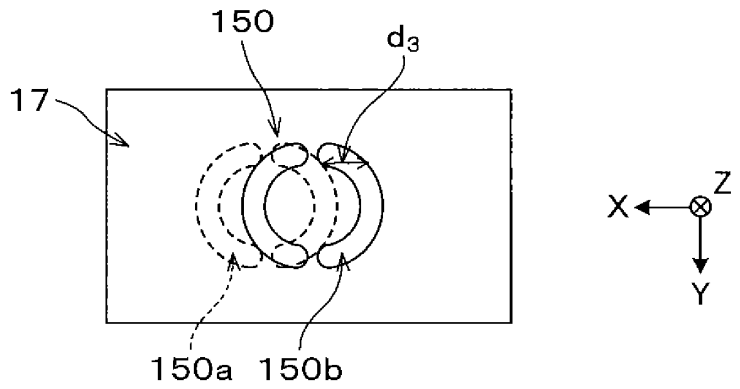
[図13]


150
d_3
17
X
Z
Y
150a
150b

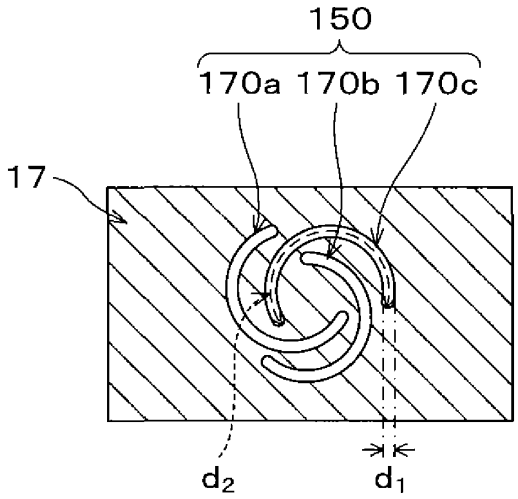
[図14]


150
170a
170b
17
d_2
d_1

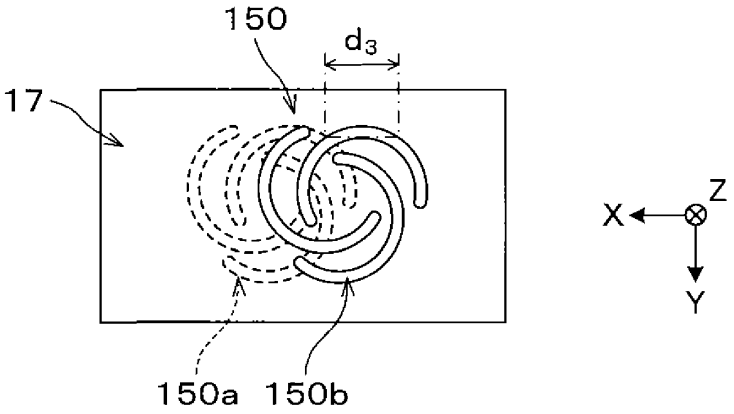
[図15]


150
d_3
17
X
Z
Y
150a
150b

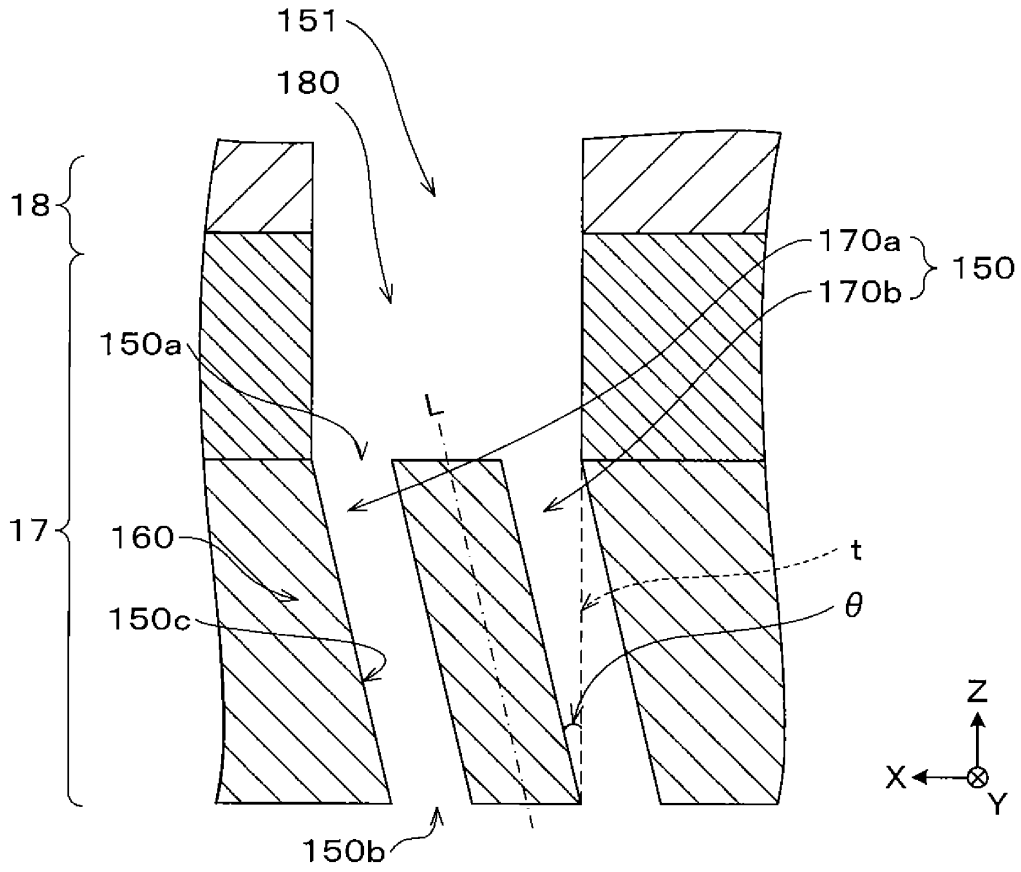
[図16]



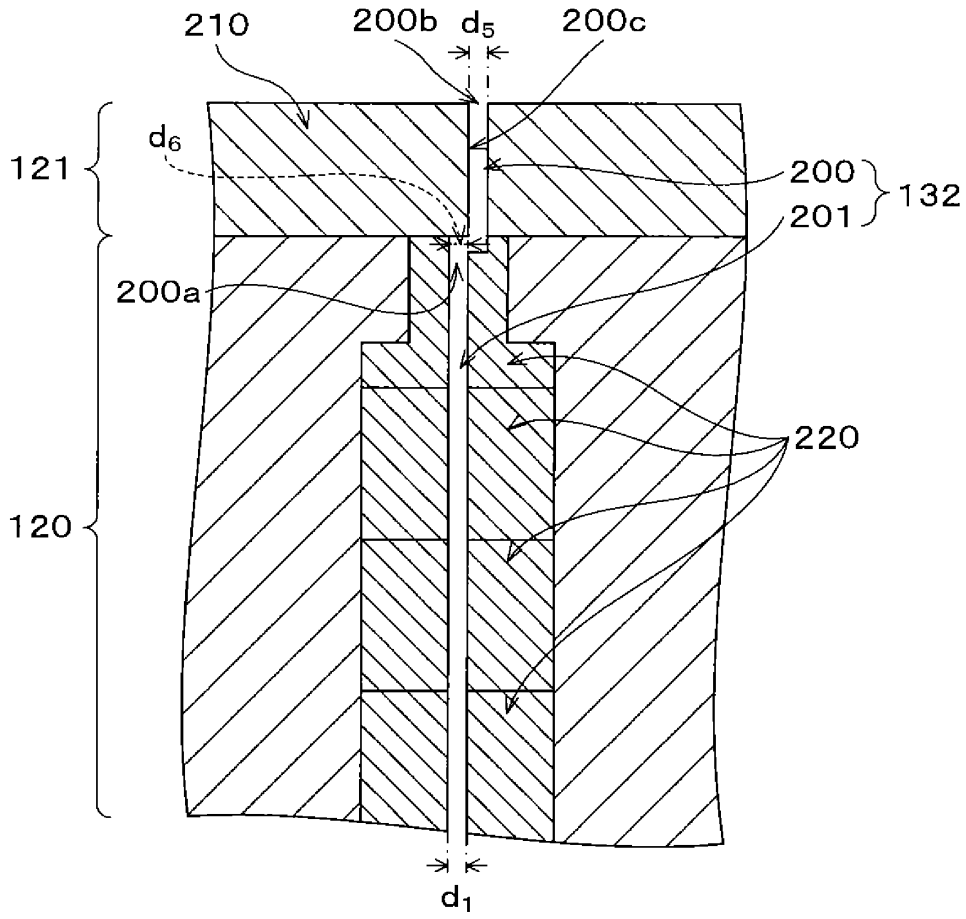
[図17]



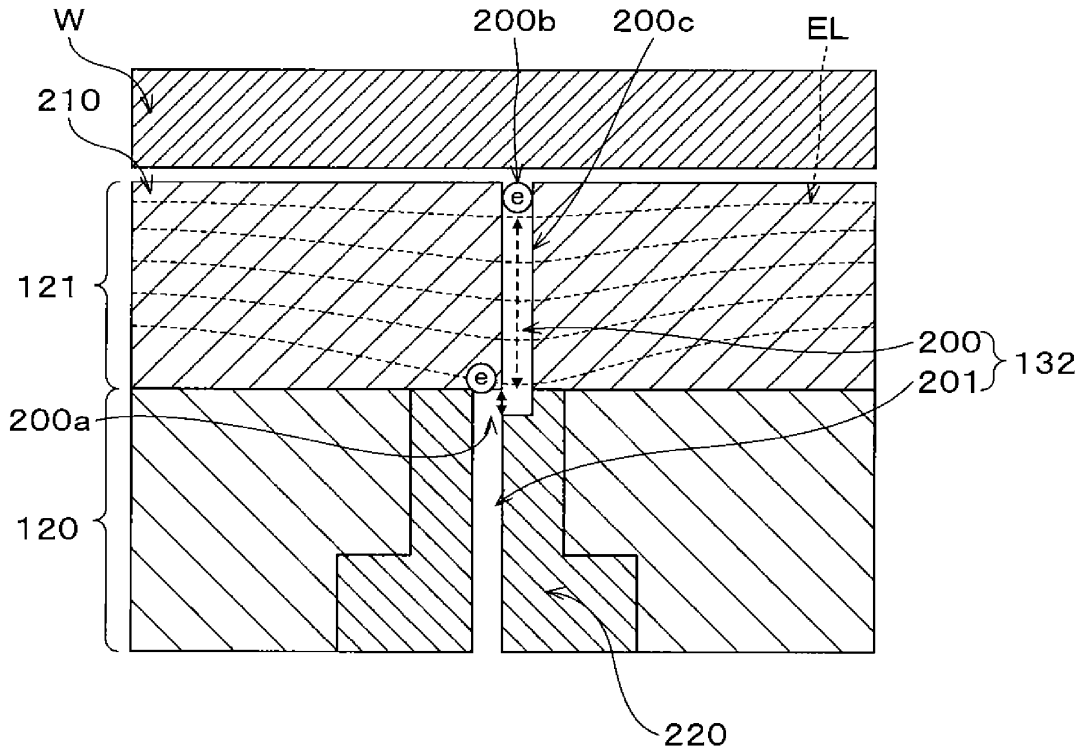
[図18]



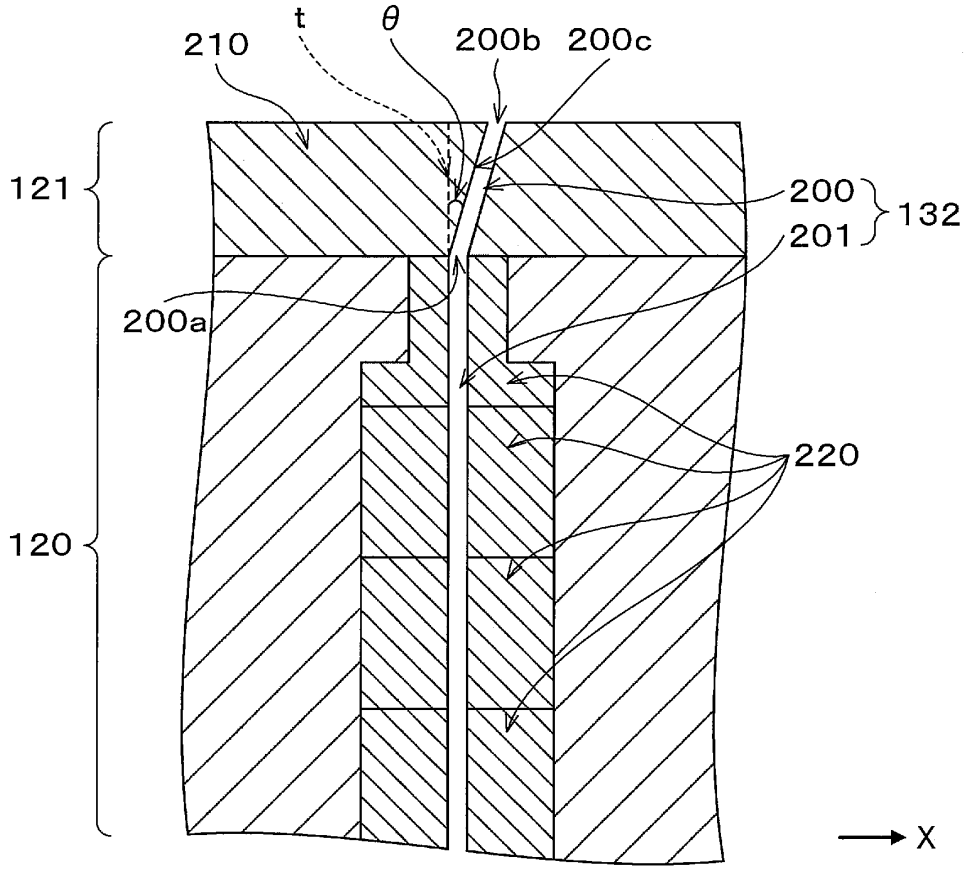
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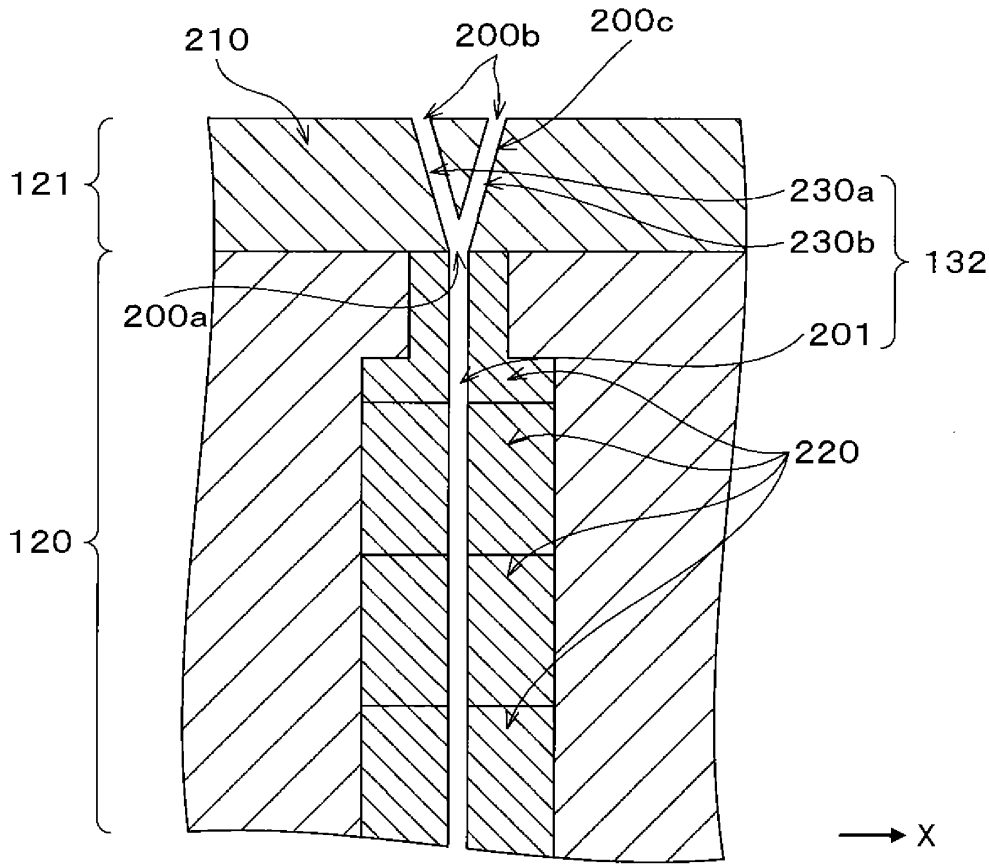
[図20]



[図21]



[図22]



[図23]

